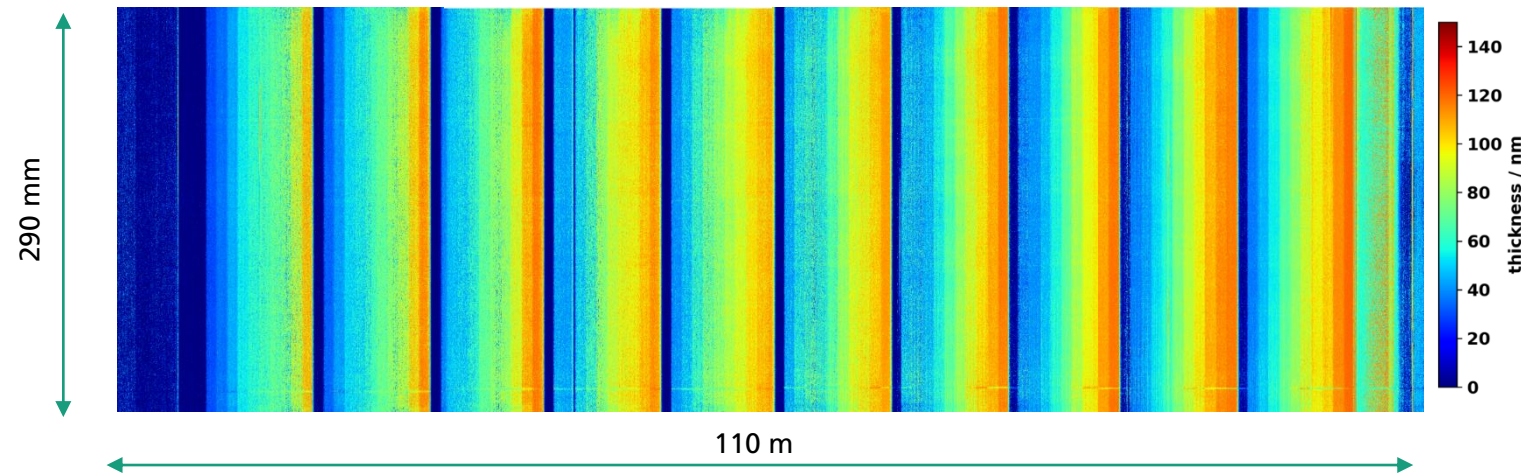


LARGE AREA FUNCTIONAL THIN FILM PROPERTIES MAPPING USING *IN-LINE* HYPERSPECTRAL IMAGING DURING ROLL-TO-ROLL MAGNETRON SPUTTER DEPOSITION

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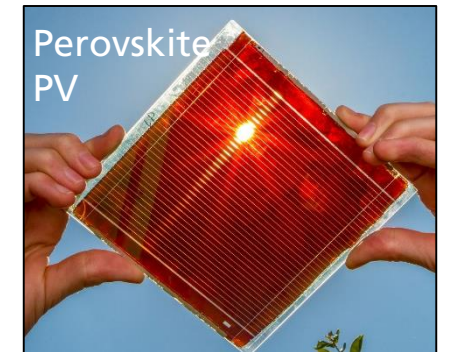
The challenge

- **We need** precise ($< \pm 1\%$) control of
 - Thin film thickness
 - chemical composition
 - Solid-state phase / crystallinity
 - Surface roughness / morphologyin thin film processing on large area in multilayer stacks
- **We miss** *fast, efficient and accurate* methods to measure
 - thickness of ultrathin transparent layers (≤ 100 nm)
 - individual layer properties in multilayers
 - „in-situ“ access to solid state phase
 - access to nano-roughness / density
 - inline access to functional properties



source: EControl-Glas, GmbH, Plauen

Question:
How can we map/image the (in)homogeneity of relevant thin film properties on large areas (up to 100m²) at high speed?



www.solliance.eu

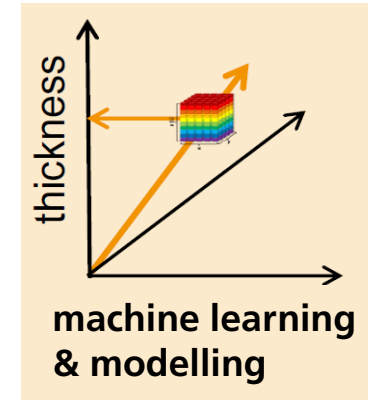
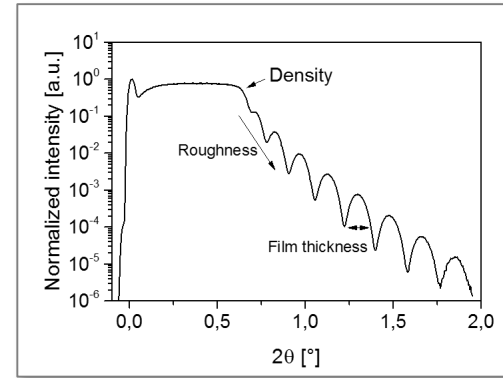
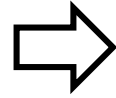


NanoQI concept

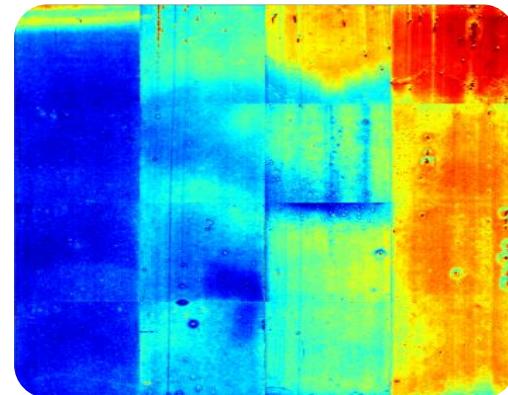
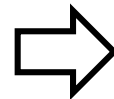
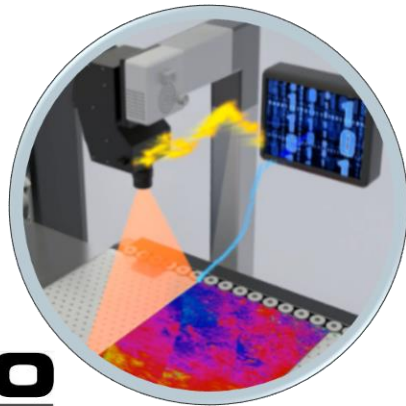
high-speed at-line / in-line

XRR / XRD

tu technische universität dortmund



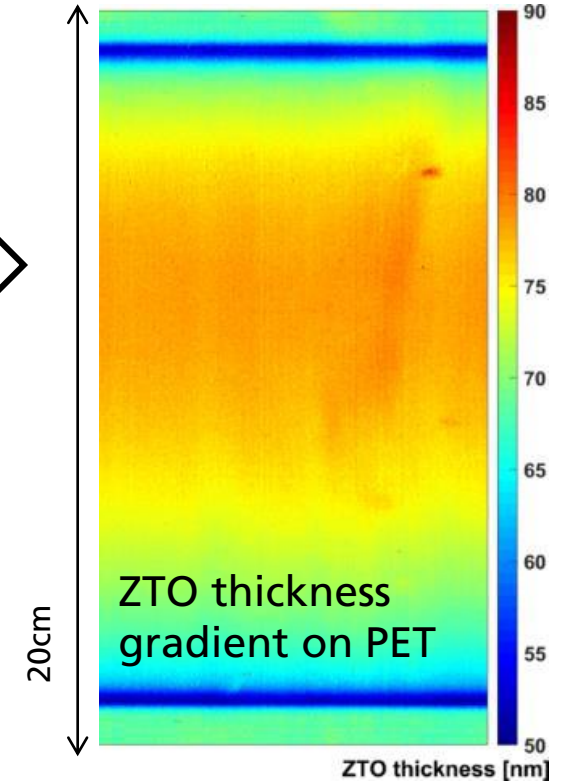
- fast large area surface inspection
- nano material quality control
- real-time process feedback



Fraunhofer
IWS

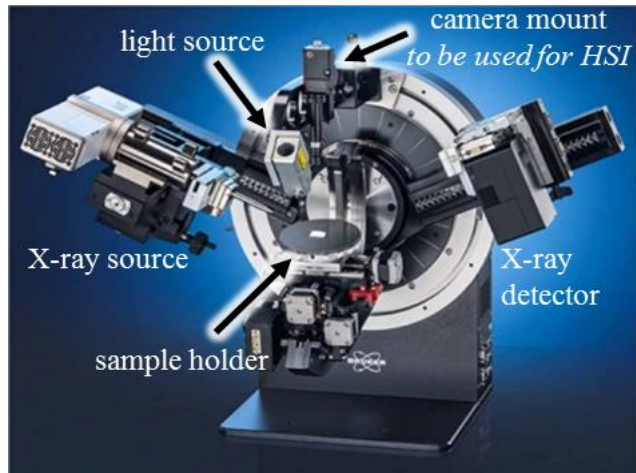
neo
NORSK ELEKTRO OPTIKK AS
HySpex

Fraunhofer
FEP



web transport direction

NanoQI methods

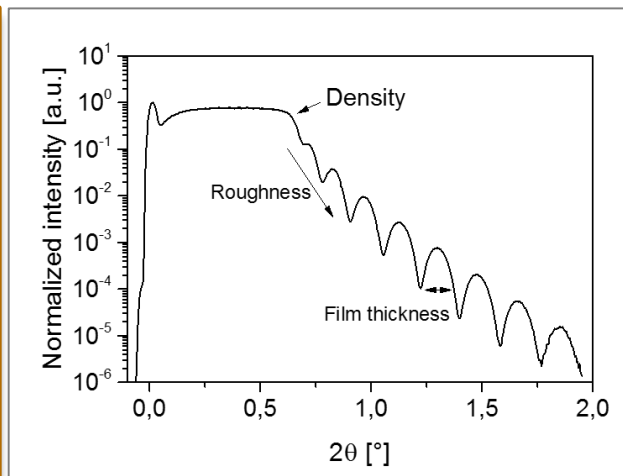
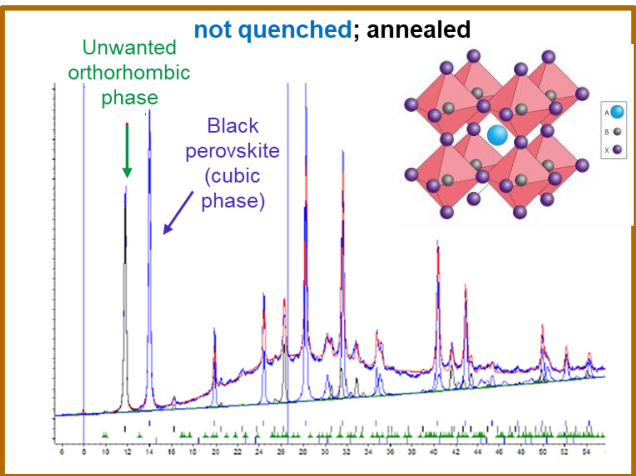


- **X-ray diffraction analysis**

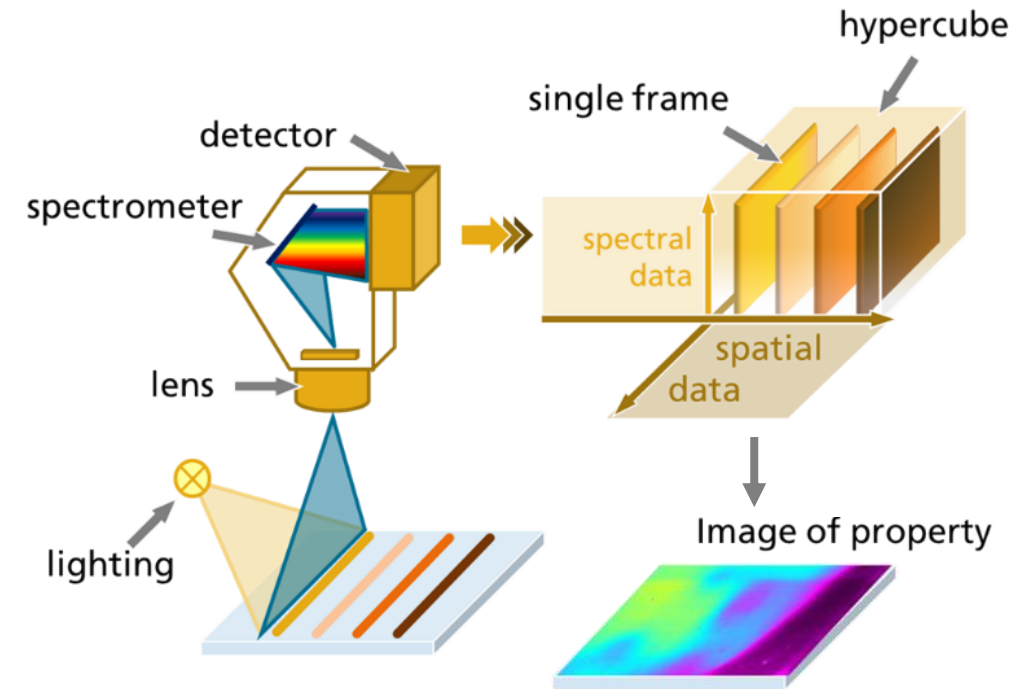
- Phase analysis
- Chemical composition

- **X-ray reflectometry**

- Thickness / Multilayers
- Roughness
- (electron) density



- High-speed & high accuracy semi-automated sample evaluation for quality control & HSI model training (calibration)



- **Hyperspectral Imaging**

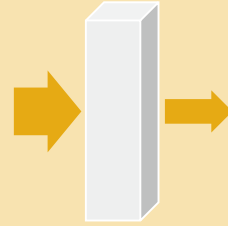
- 2D Spatially resolved optical transmission/ reflection spectrometry
- Detect defects, gradients, property drifts
- Large area imaging of functional properties
- Inline integration to thin film processing

Data evaluation options for HSI data

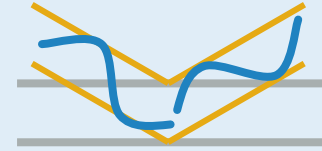
Hard modeling

Physical description of received data set

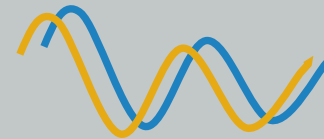
- Could be slow
- No external ground truth needed



Lambert-Beer's law
 $E = \varepsilon * c * d$



Bragg's law
 $n * \lambda = 2 * d * \sin \theta$

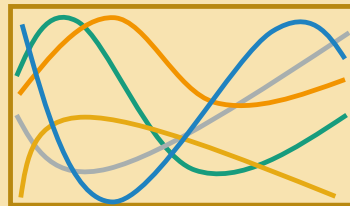


Dielectric function
 $\varepsilon(\omega) = \varepsilon_{\infty} - [\varepsilon_0 \rho (\omega^2 \tau + i \omega)]^{-1}$

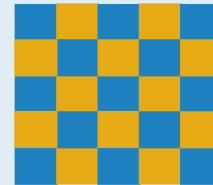
Soft modeling

Pattern recognition by means of un-/supervised data evaluation algorithms

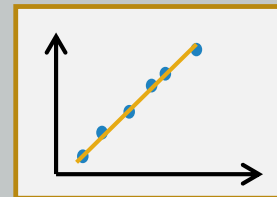
- Could be fast
- Prediction model must be trained



Spectral pattern recognition, chemometrics (i. e. PCA, LDA, SIMCA)

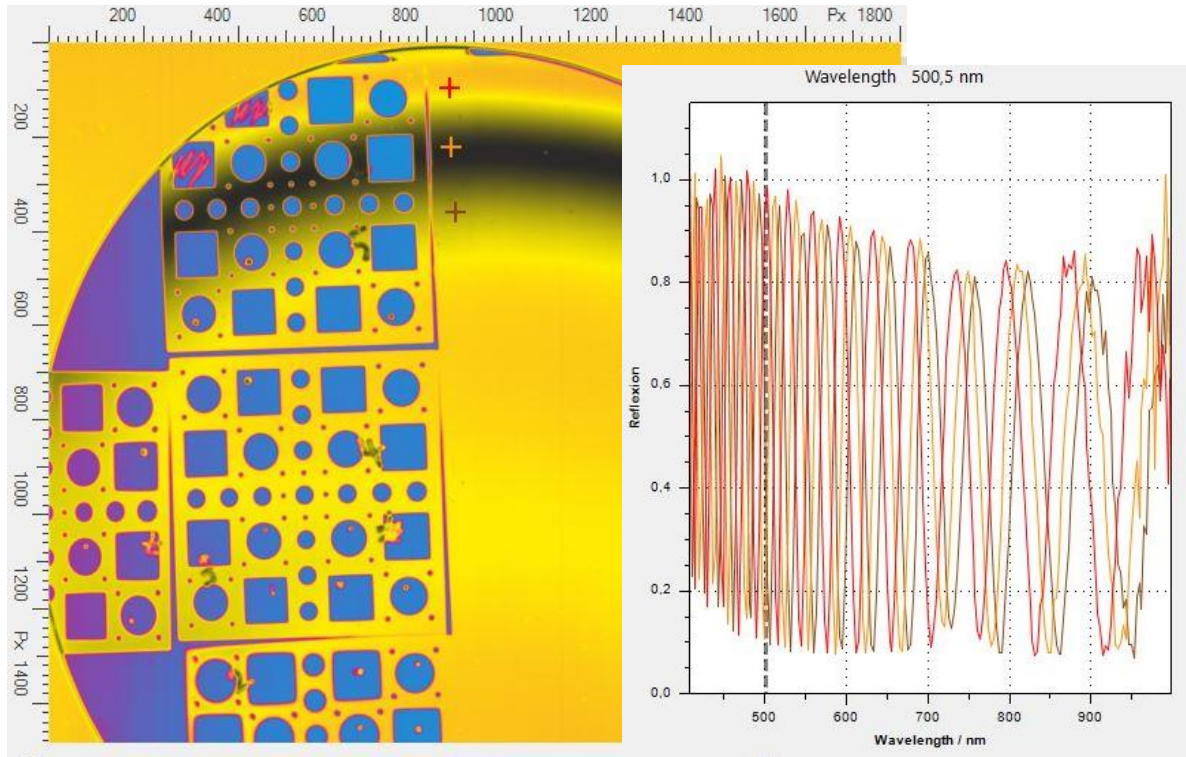


graphical pattern recognition (i. e. wavelet analysis)



multivariate correlation algorithms (i. e. PLS)

HSI example: Thickness gradient modelling of AlN on Si wafer

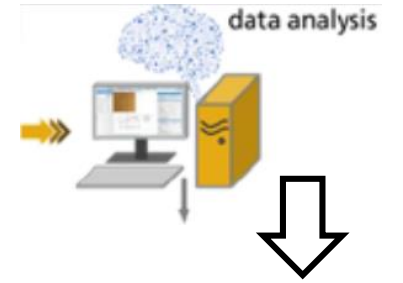


HSI reflection „image“
@ 600nm

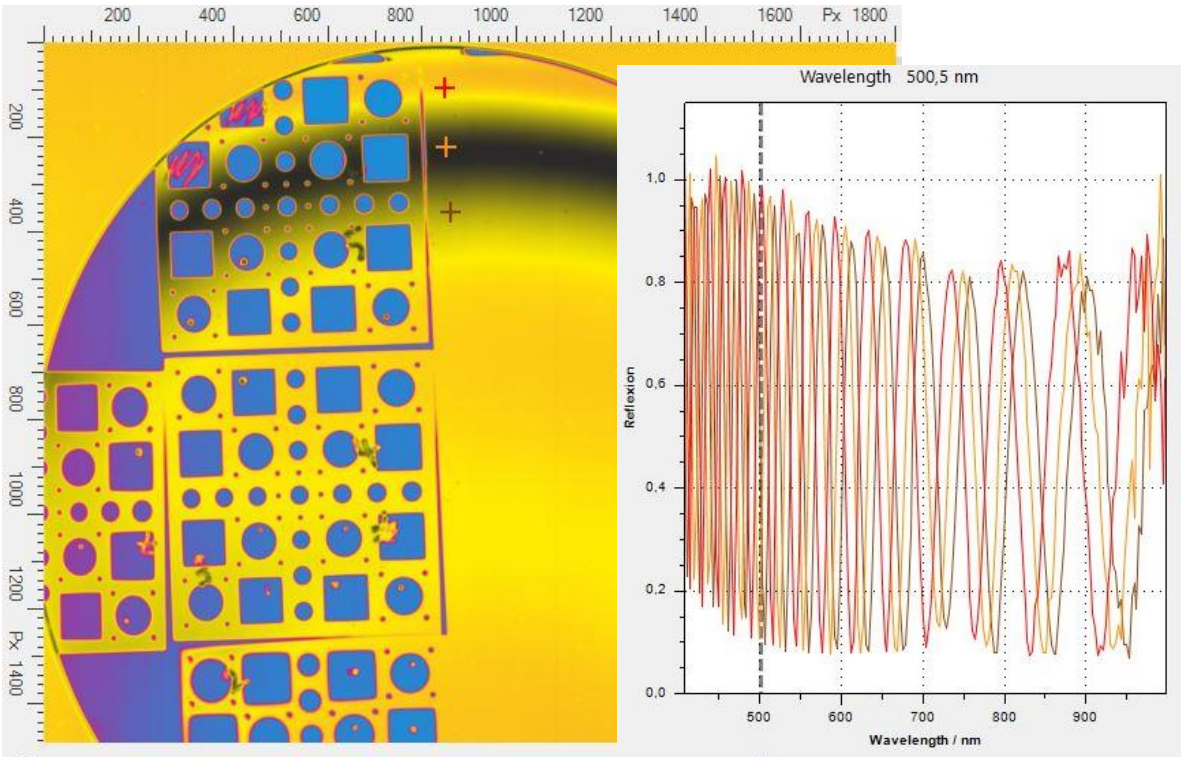
z-axis = intensity (raw data)

optical reflection spectra
at selected pixels:
interference pattern
-> thickness information

HSI example: Thickness gradient modelling of AlN on Si wafer



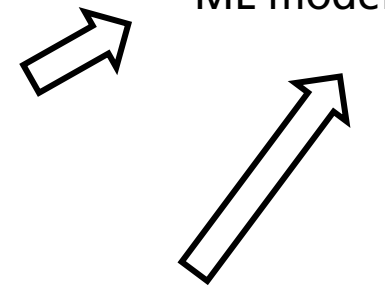
Vector normalization
 Principle Component Analysis
 ML model training & verification



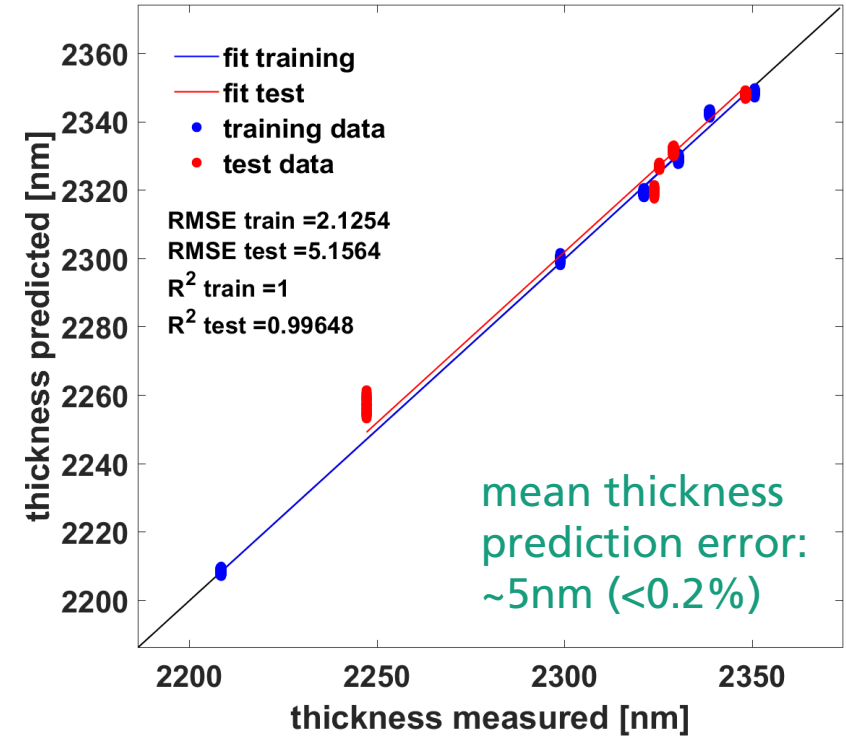
HSI reflection „image“
 @ 600nm

z-axis = intensity (raw data)

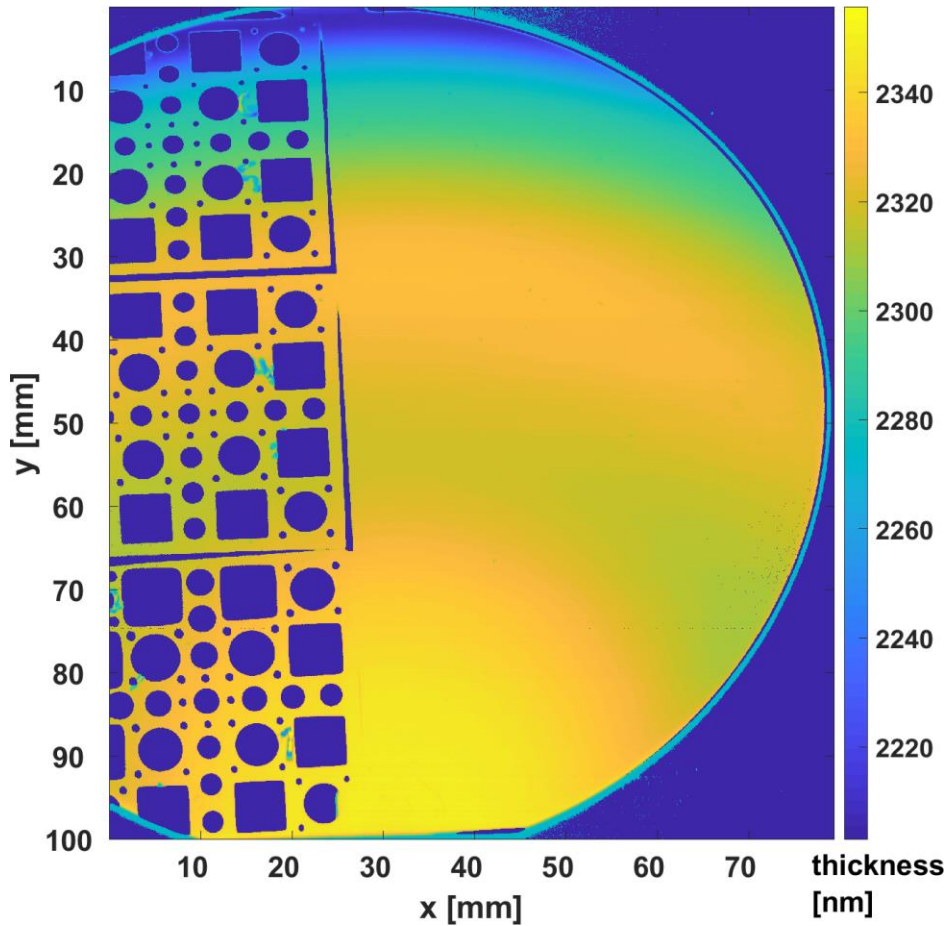
optical reflection spectra
 at selected pixels:
 interference pattern
 -> thickness information



+ 10 thickness
 values from
 locations
 across wafer by
 external method
 (spectroscopic
 ellipsometry)



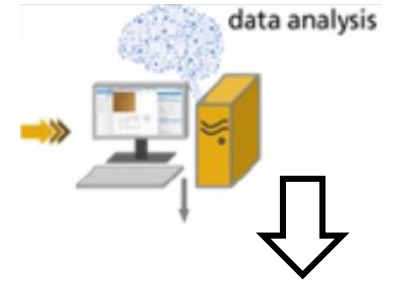
HSI example: Thickness gradient modelling of AlN on Si wafer



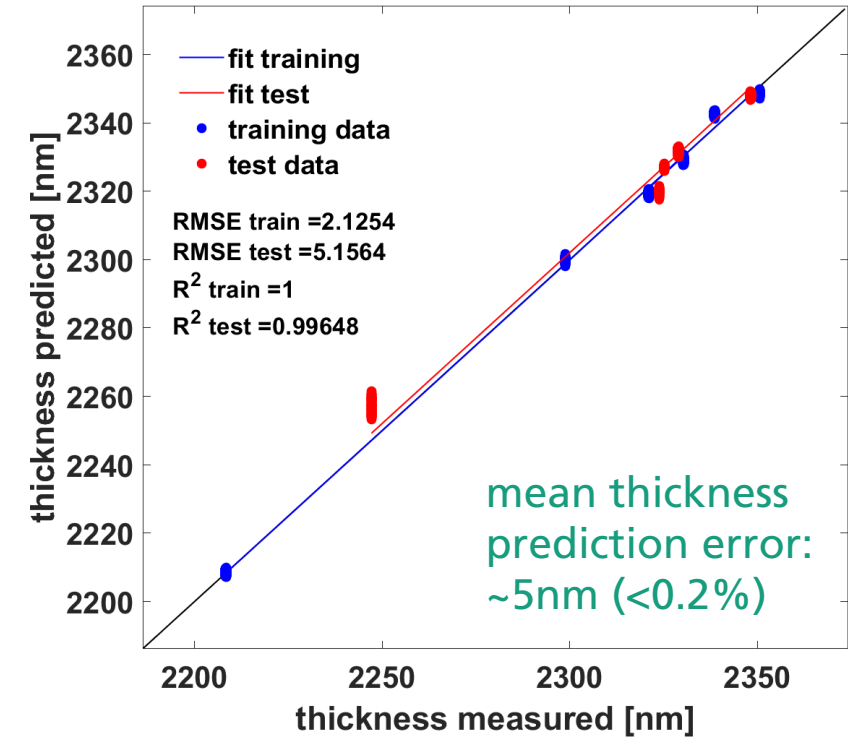
Vector normalization

Principle Component Analysis

ML model training & verification



data transformation



Result

- thickness map of complete wafer with sub-mm spatial resolution
- HSI model can now be used for any unknown AlN/Si sample (without external data)

In-line HSI @ coFlex® 600 pilot web coater: performance parameters

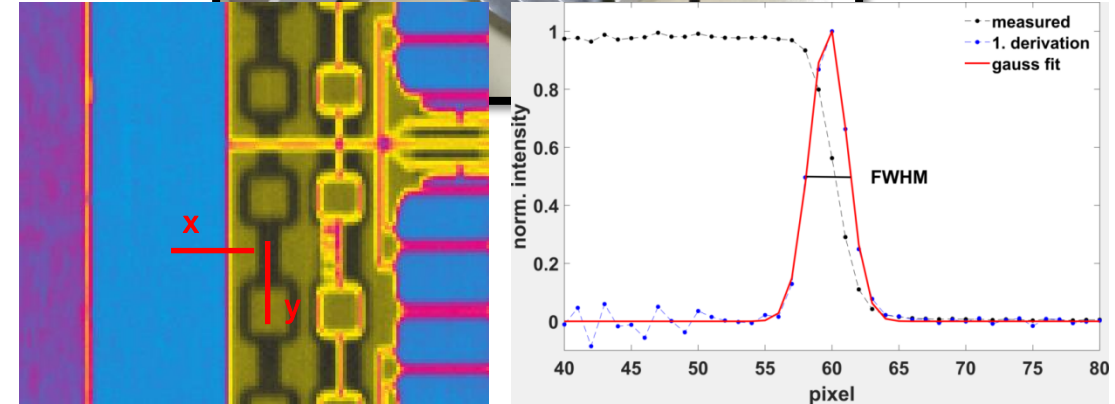
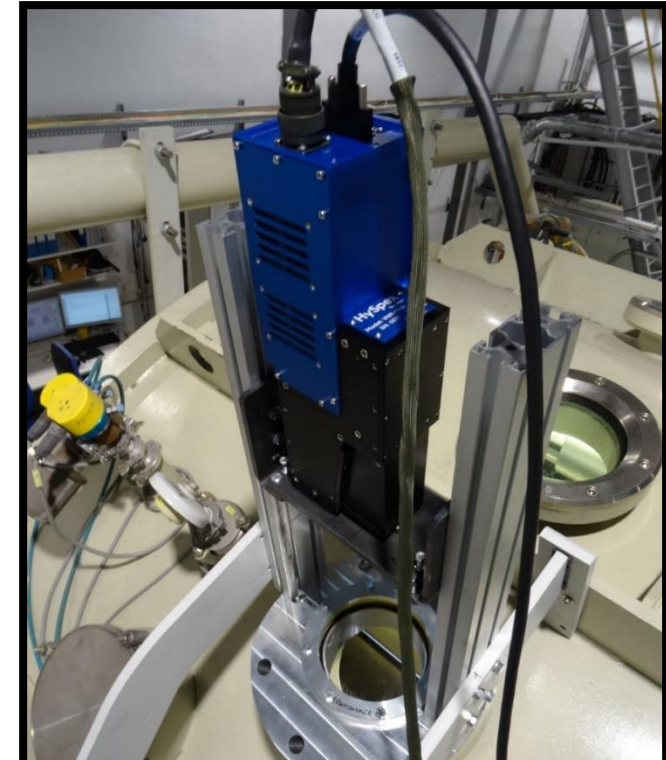
Configuration

- HSI camera working distance: 100 cm ~66 cm
- HSI camera FoV angle 16° 40°
- Web speed* <1.5 m/min ~2.5 m/min

Experimental parameters:

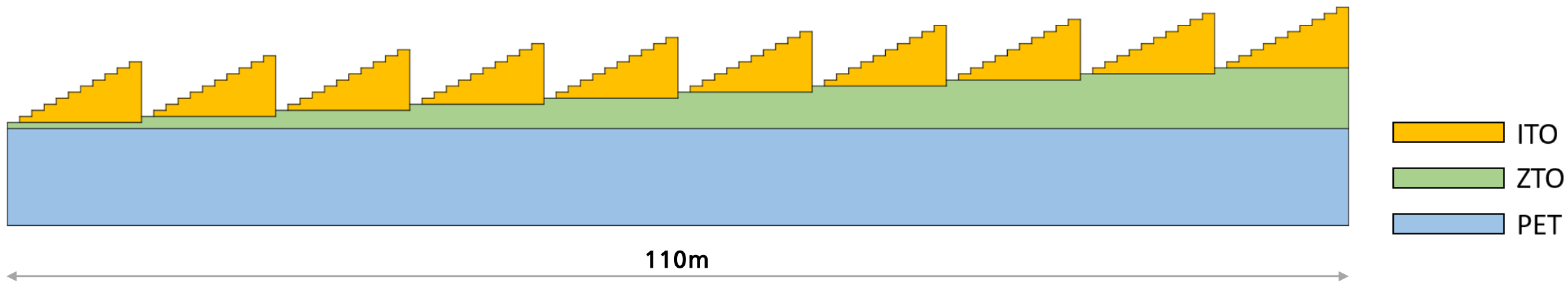
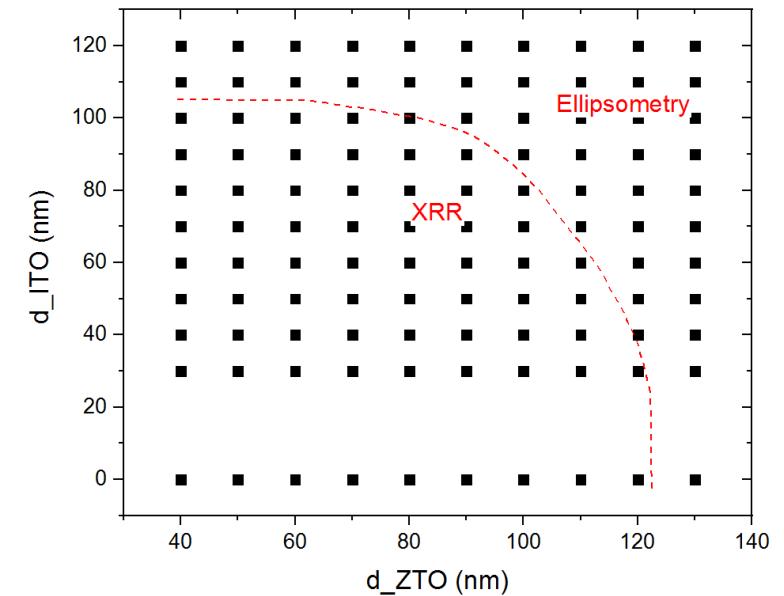
Field of View (FoV):	292 mm	450 mm
Pixel size:	0.162 mm/px	~0.3 mm/px
Spatial Resolution (using FWHM of 1st derivative)	~0.25 mm (x) ~0.70 mm (y)	~0.4 mm ~1.1 mm

- *) much higher web speed possible via
- accepting some image spatial distortion (in coating direction)
 - intelligent „online“ HSI data reduction
 - increasing HSI data bandwidth



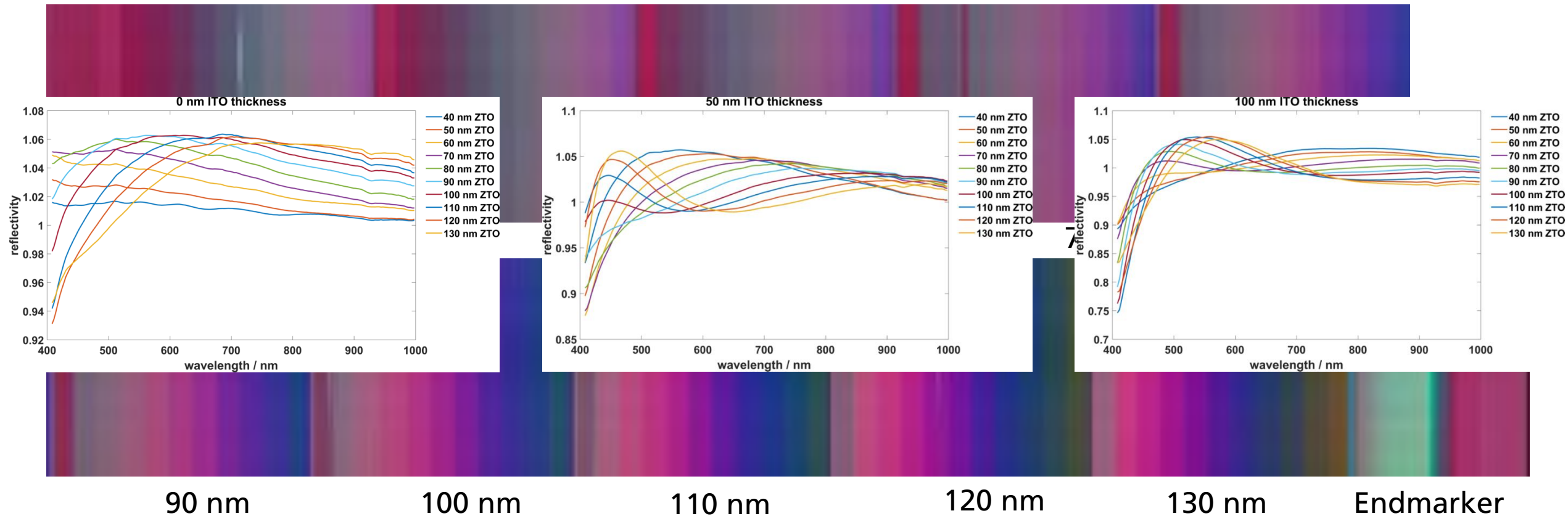
In-line HSI @ coFlex® 600 pilot web coater: performance parameters

- Transparent oxide double layer
- Complex test object for HSI on coFlex® 600
- Layer thickness determination for modeling still pending



In-line HSI @ coFlex® 600 pilot web coater: performance parameters

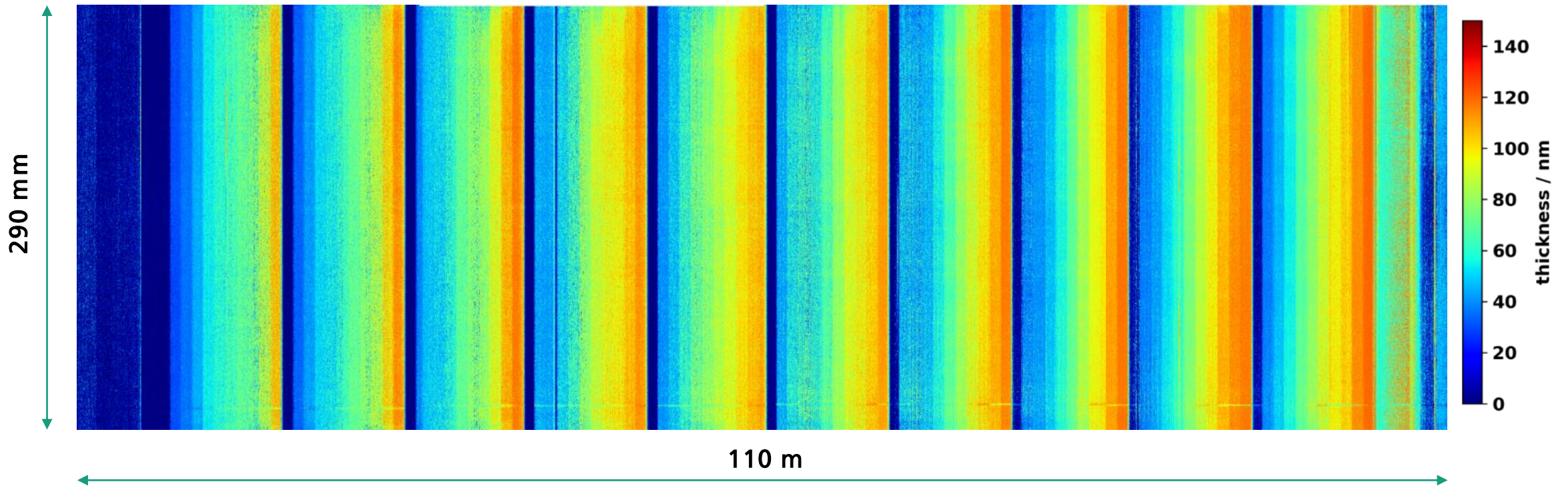
- PCA of the referenced (and normalized) spectra makes spectral differences visible!
- Target: RGB image of the first 3 PCs: different color = different spectral properties



- Different areas of the 10 nm steps are clearly visible → Input for HSI Model

In-line HSI @ coFlex® 600 pilot web coater: performance parameters

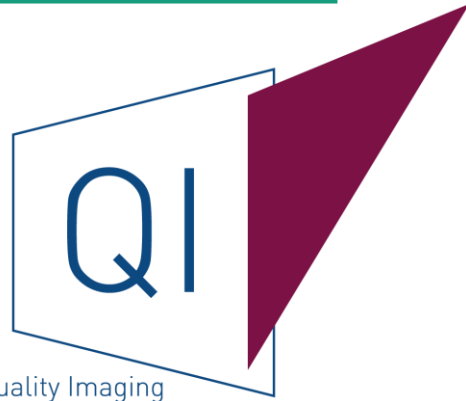
Nanoscale, flexible & functional inline method for Materials research and development on large industrial surfaces is just around the corner!



Thank you for listening

NANO

Multimodal X-ray and Hyperspectral
Thin-Film Nanomaterial Evaluation and Quality Imaging



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